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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet	1	of	5

Complete if Known	
Application Number	10/782,481
Filing Date	02/18/2004
First Named Inventor	Arthur Telkamp
Art Unit	2874
Examiner Name	Not yet assigned
Attorney Docket Number	703427.4004

U.S. PATENT DOCUMENTS

Examiner Initials	Cite No.[1]	U.S. Patent Document Number/Kind Code[2] (if known)	Publication Date MM/DD/YYYY	Name of Patentee or Applicant of Cited Document
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Examiner Signature		Date Considered	8-6-05

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Sheet 2 of 5

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Substitute for form 1449A/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	10/782,481
				Filing Date	02/18/2004
				First Named Inventor	Arthur Telkamp
				Art Unit	2874
(use as many sheets as necessary)				Examiner Name	Not yet assigned
Sheet	3	of	5	Attorney Docket Number	703427.4004

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Application Number	10/782,481
	Filing Date	02/18/2004
	First Named Inventor	Arthur Telkamp
	Art Unit	2874
(use as many sheets as necessary)	Examiner Name	Not yet assigned
Sheet 4 of 5	Attorney Docket Number	703427.4004

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Examiner Signature		Date Considered	8-6-07

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